Receipt date: 04/26/2006

	Application Number		10595434		
JEODINATION DIGGL COURT	Filing Date		2006-04-19		
NFORMATION DISCLOSURE STATEMENT BY APPLICANT	First Named Inventor	Siegf	ried Karg		
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	1	Yau S T et al: "Laser-Assisted Deposition of Nanometer Structures Using A Scanning Tunneling Microscope" Applied Physics Letters, American Institute of Physics, New York, US, vol. 57, no. 27, 31 December 1990, pages 2913-2915 XP000222958 ISSN: 0003-6951 the whole document  Shtokman M I. "Possibility of Laser Nanomodification of Surfaces by Means of a Scanning Tunneling Microscope" Optoelectron Instrum Data Process; Optoelectronics, Instrumentation and Data Processing (English Translation of Avtometrya) 1999, no. 3 1999 pages 27-37, XP009043144 page 27, paragraph 1 pages 28-29 pages 33-36						
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